

Summary

(1) Nature and Quantity

Inductively coupled plasma Etching system 1set

(2) Location of Work or Location of Implementation

6-6 Asahigaoka, Hino-shi, Tokyo, Japan

Tokyo Metropolitan University Hino Campus, Building, No.6 Clean room

(3) Work Period or Implementation Period

September 29, 2023

(4) Time Limit of Tender by electronic bidding

1:30 p.m. on September 28 (Wednesday), 2022

(5) Inquiry Section regarding Notice of Tender

Contract Section, Accounting Division, General Affairs Department, Tokyo Metropolitan
Public University Corporation